

**FIG. 1**

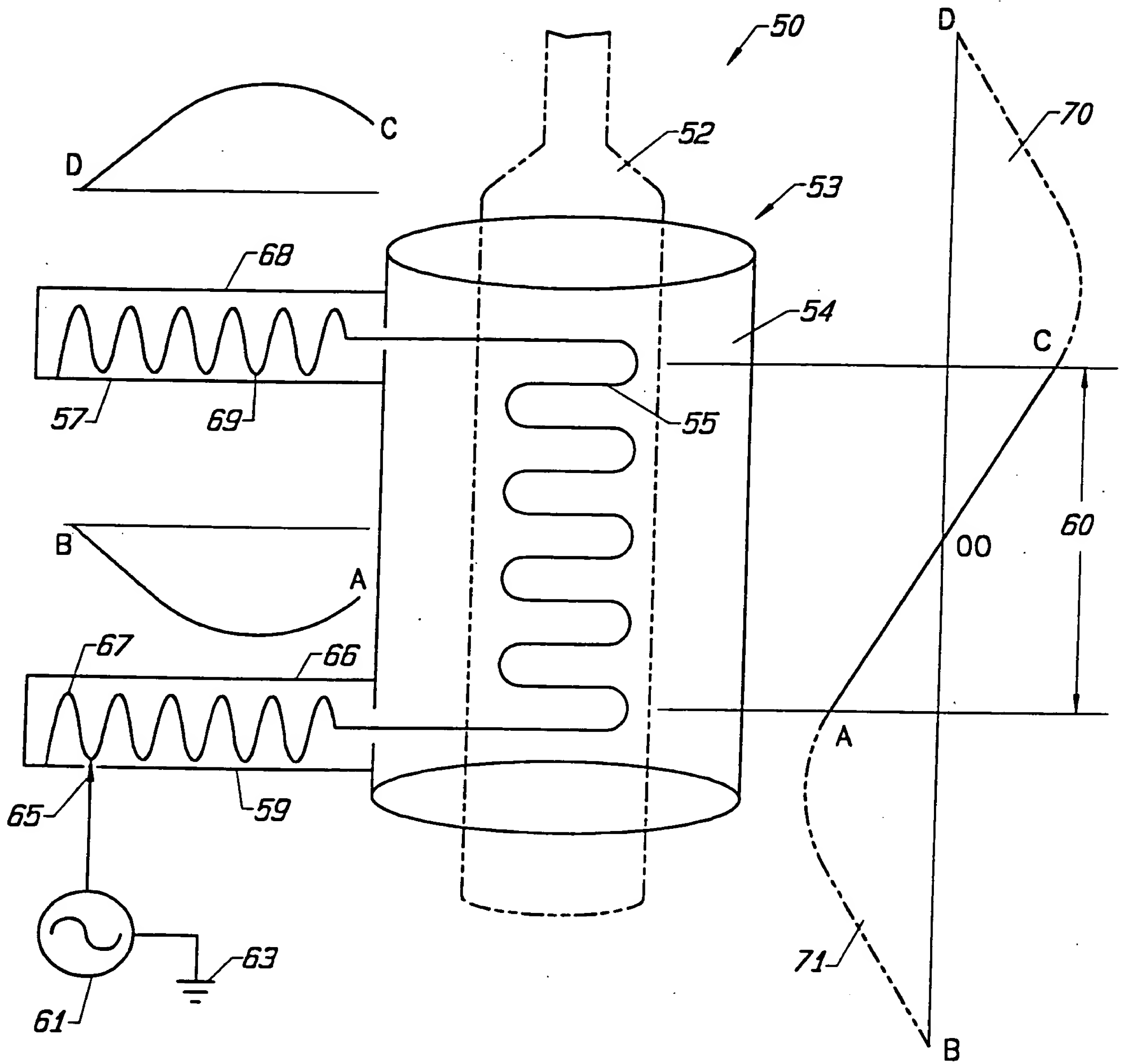
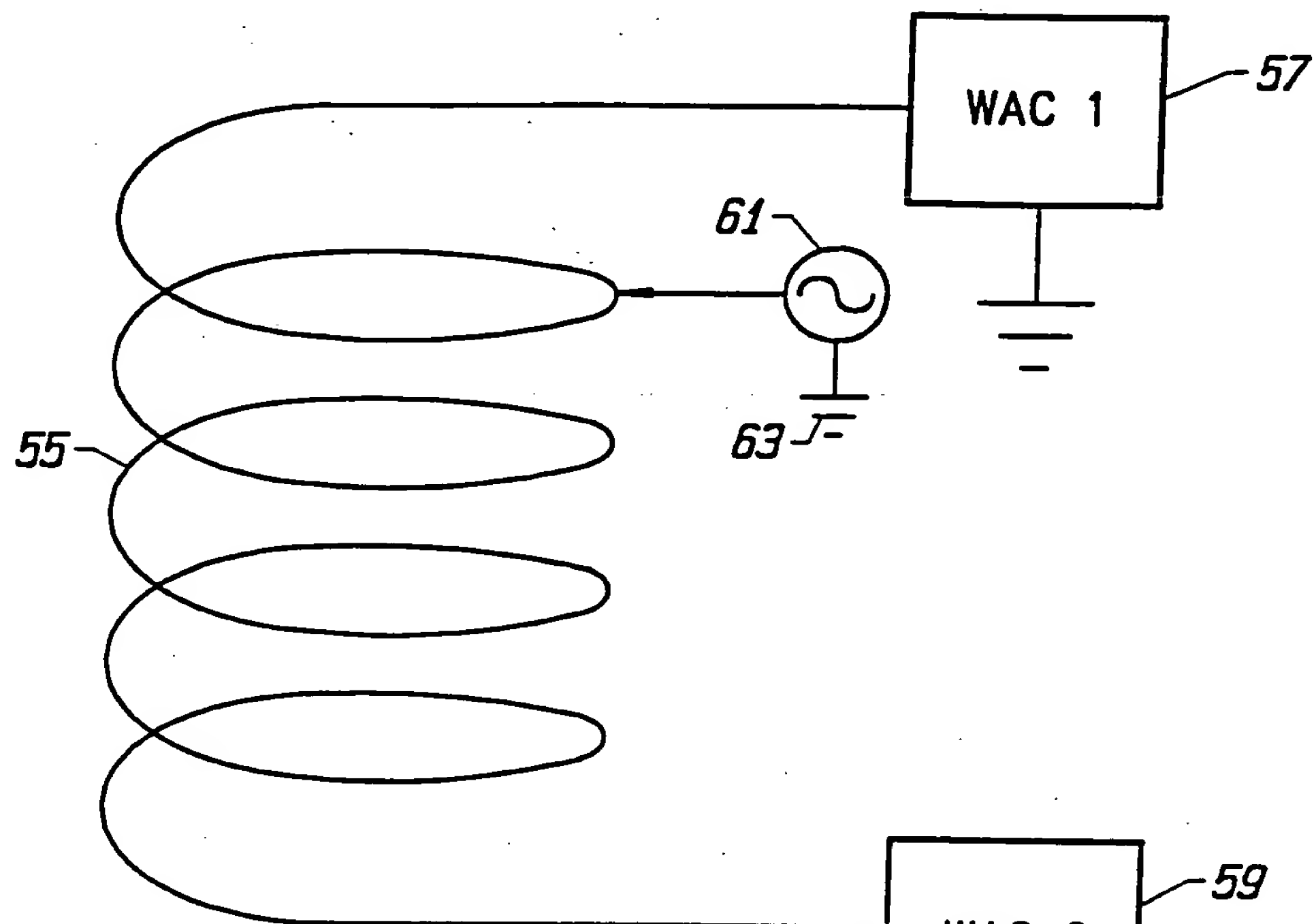
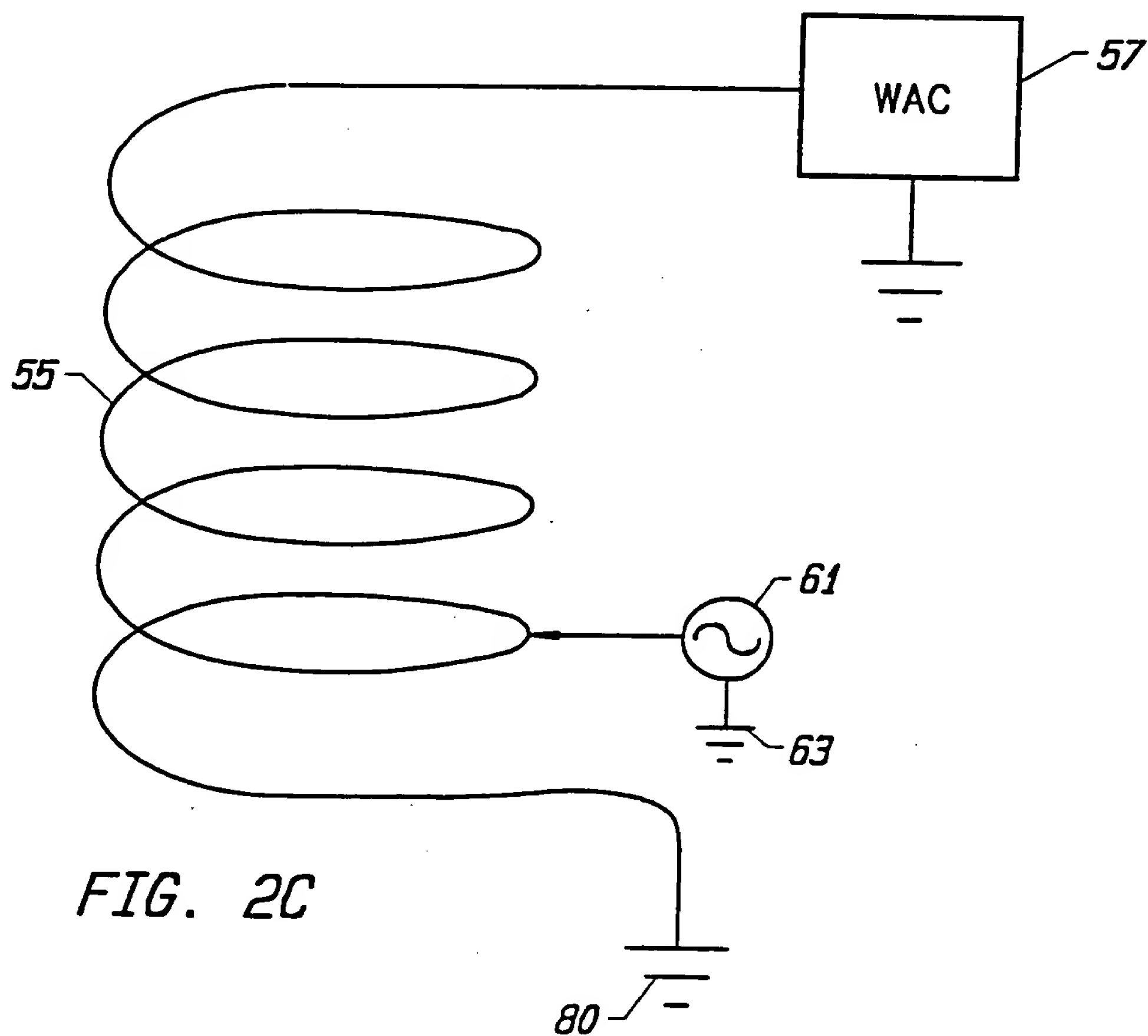


FIG. 2A



**FIG. 2B**



**FIG. 2C**

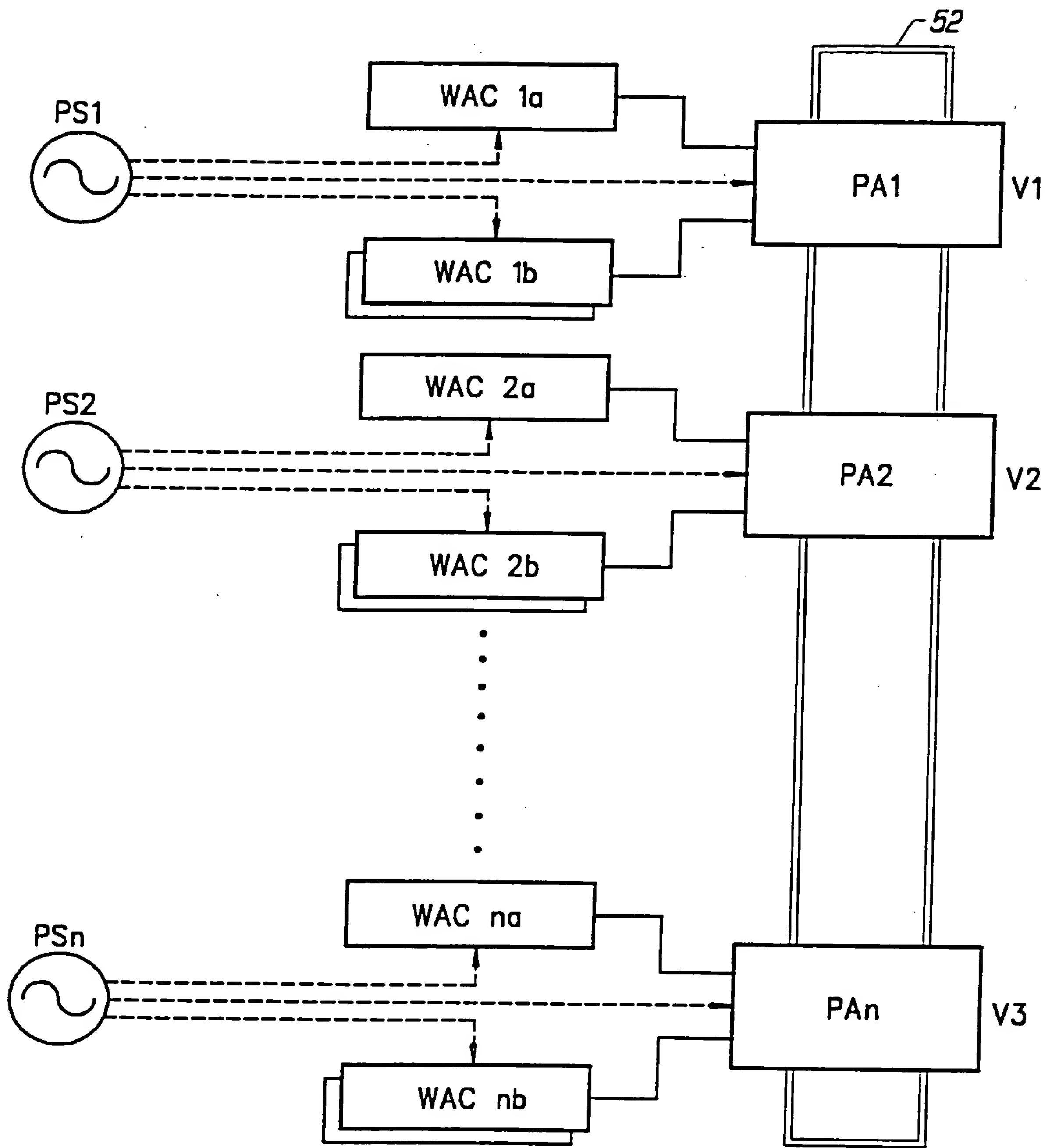
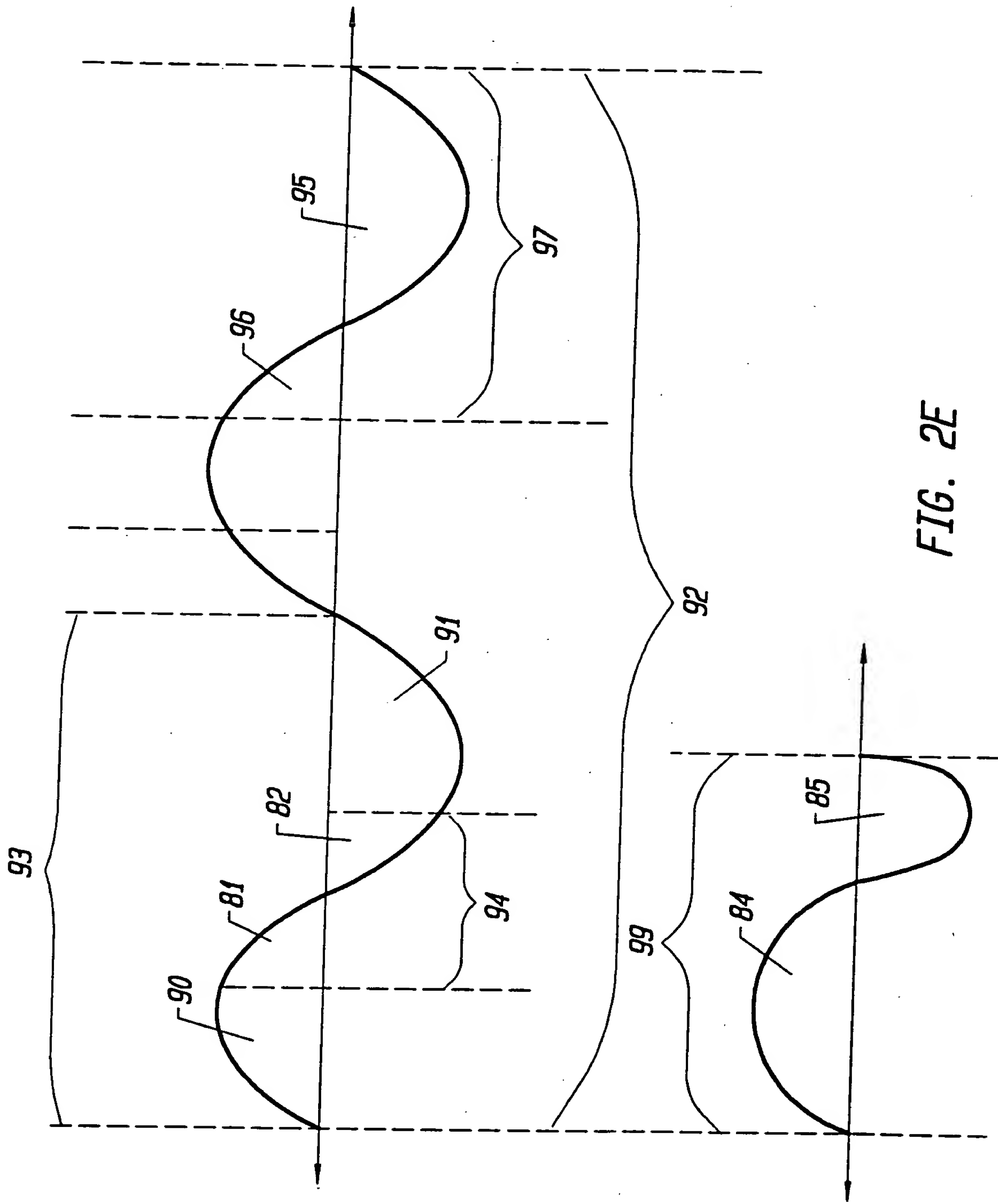


FIG. 2D



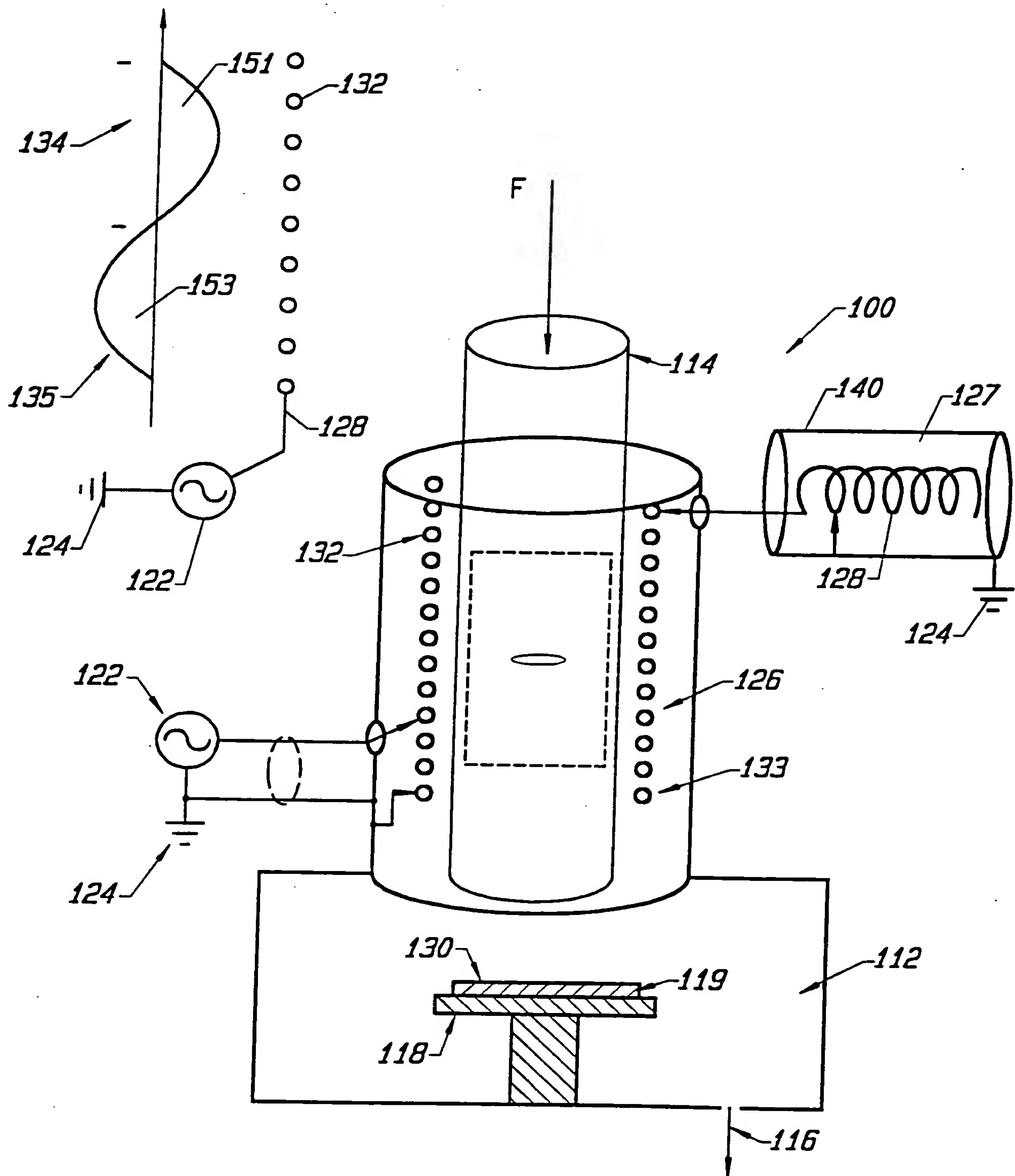


FIG. 3

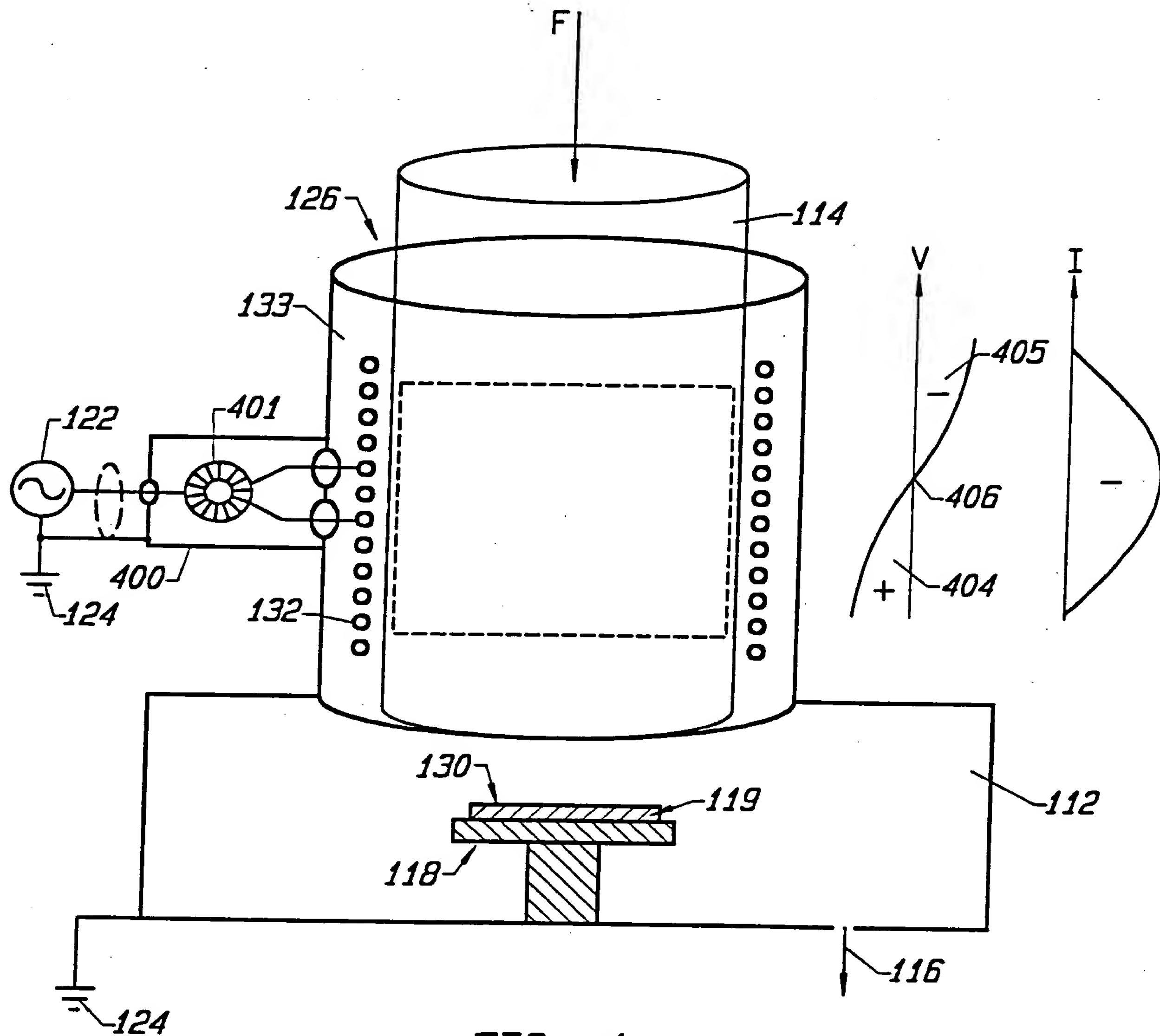


FIG. 4

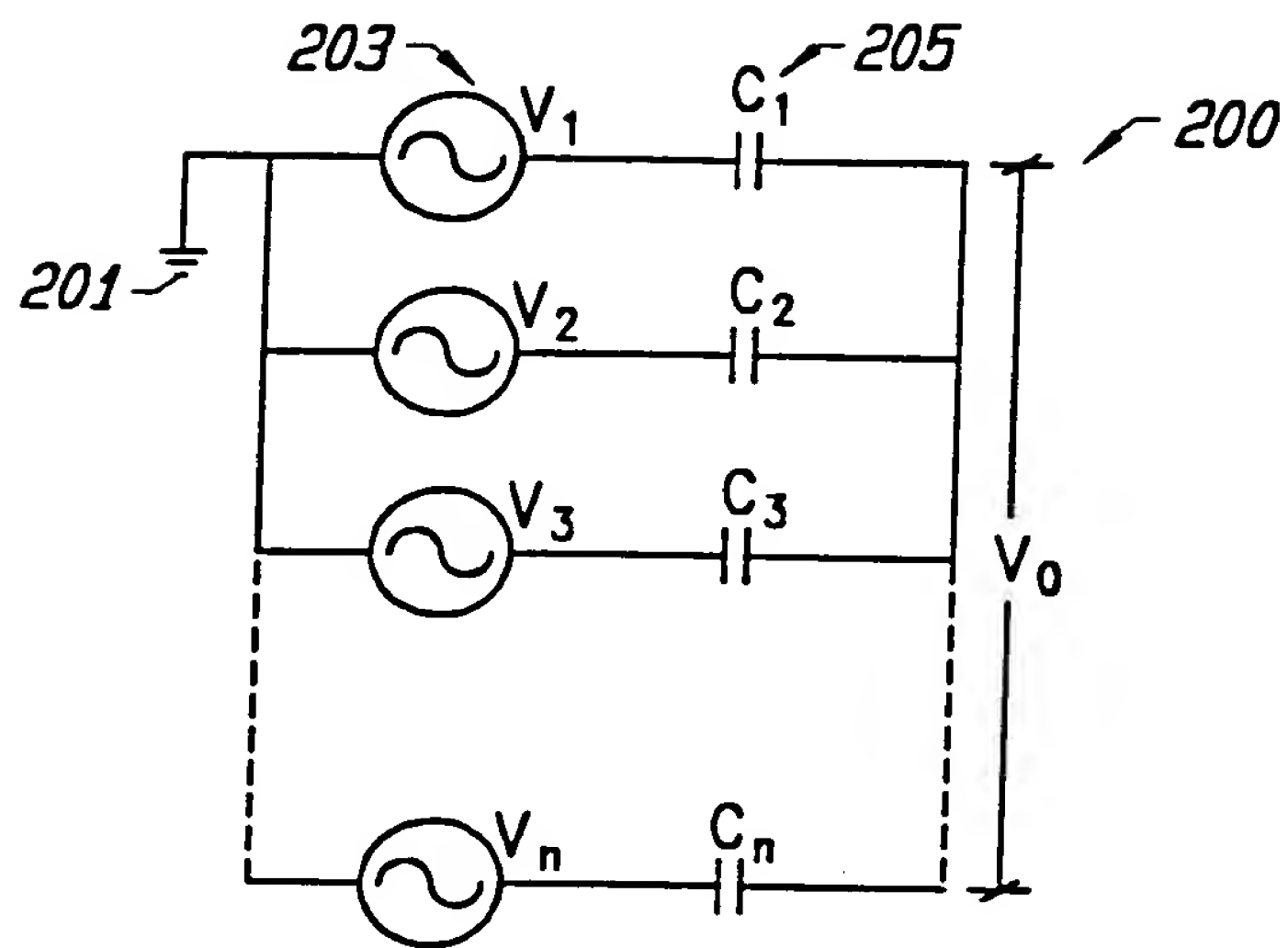


FIG. 5A



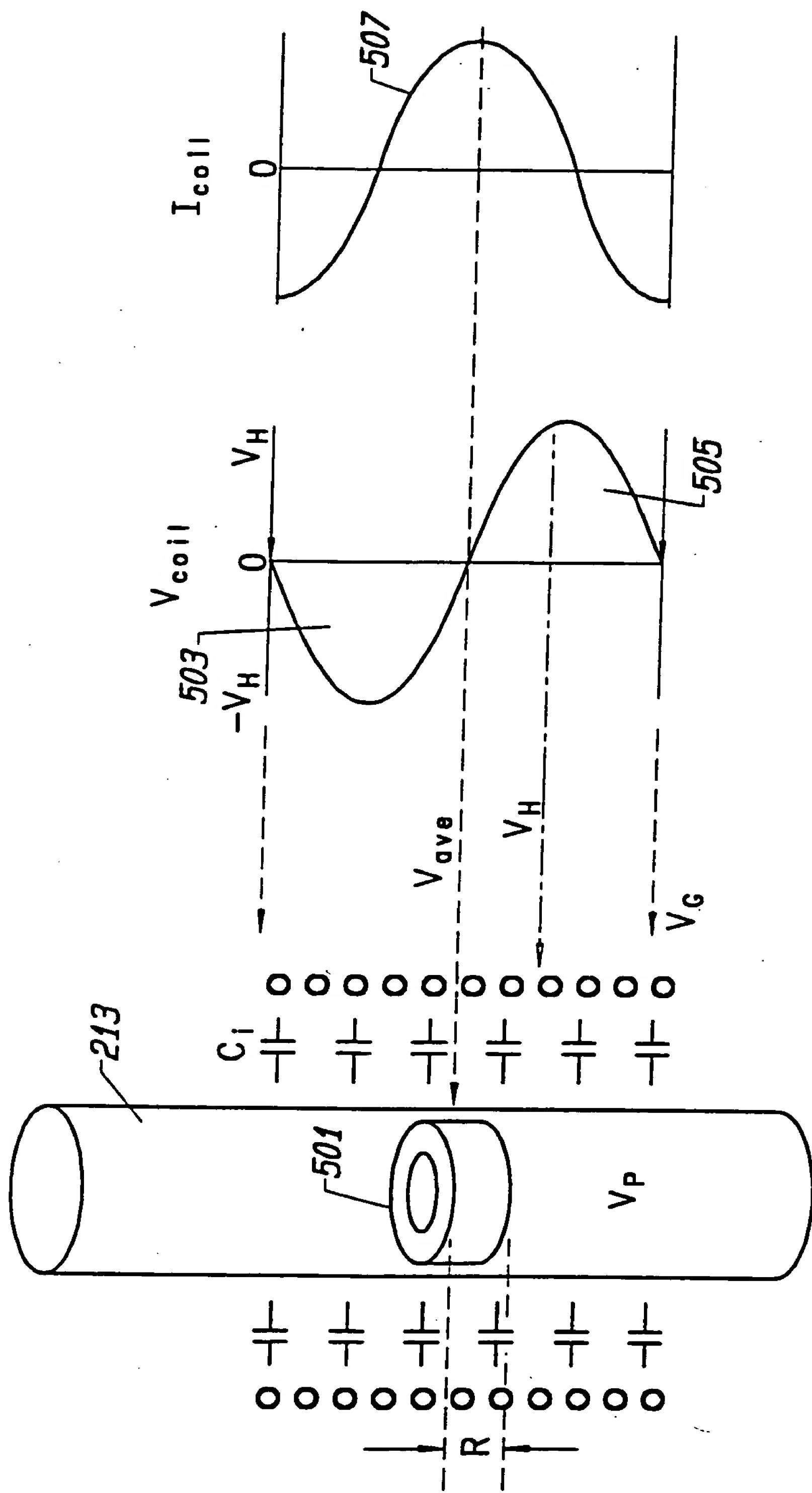


FIG. 5B

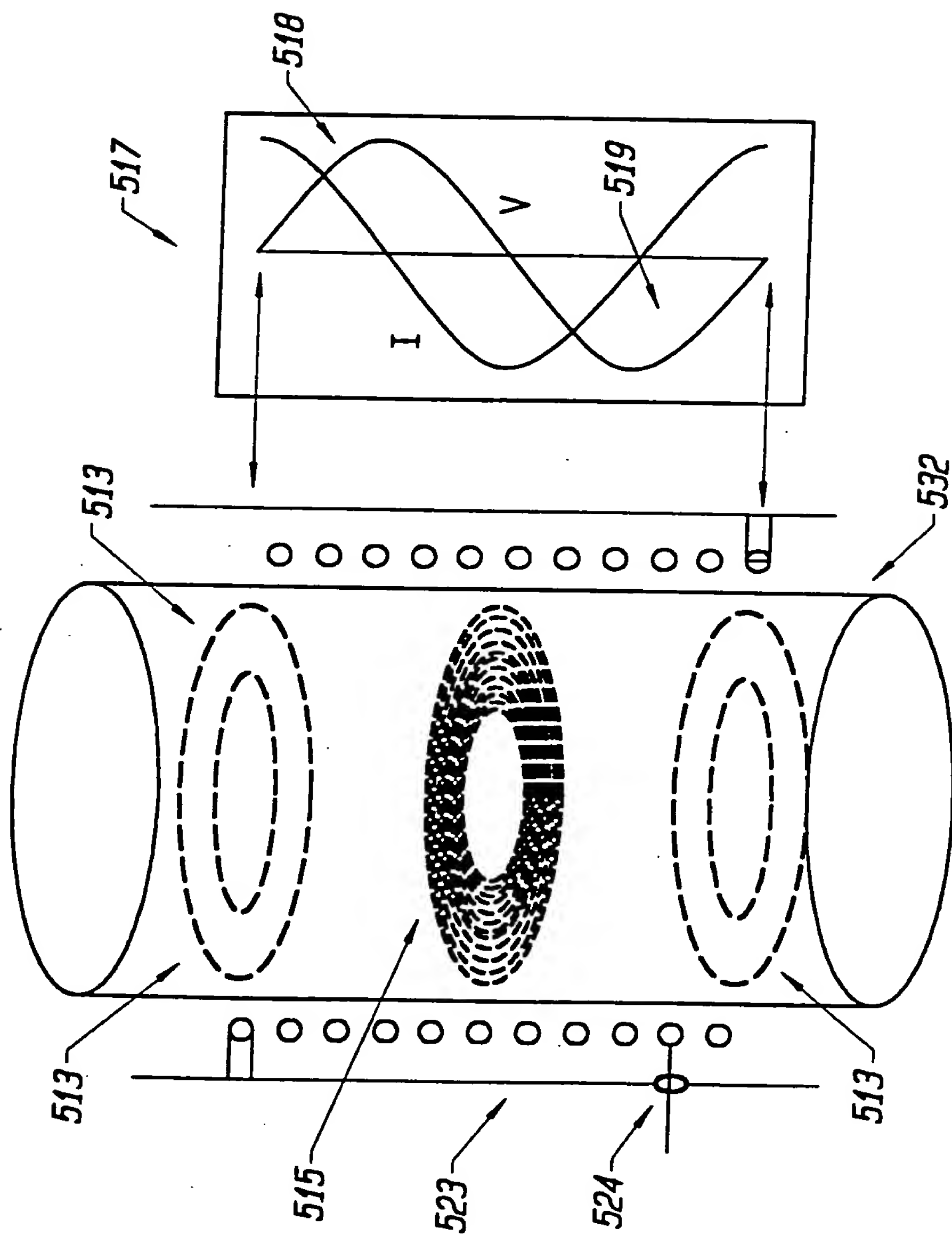
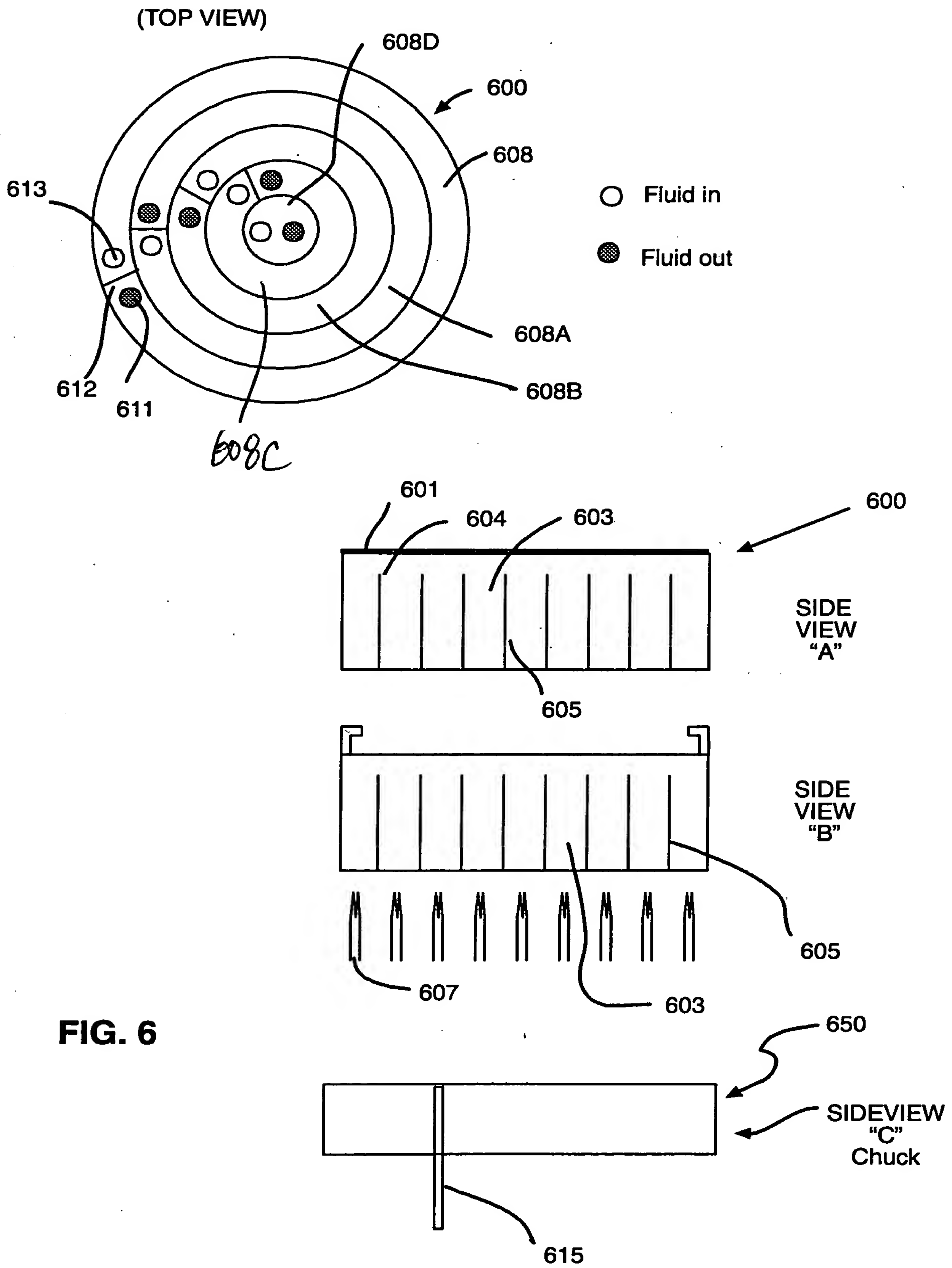


FIG. 5C

FIG. 6



**FIG. 6**

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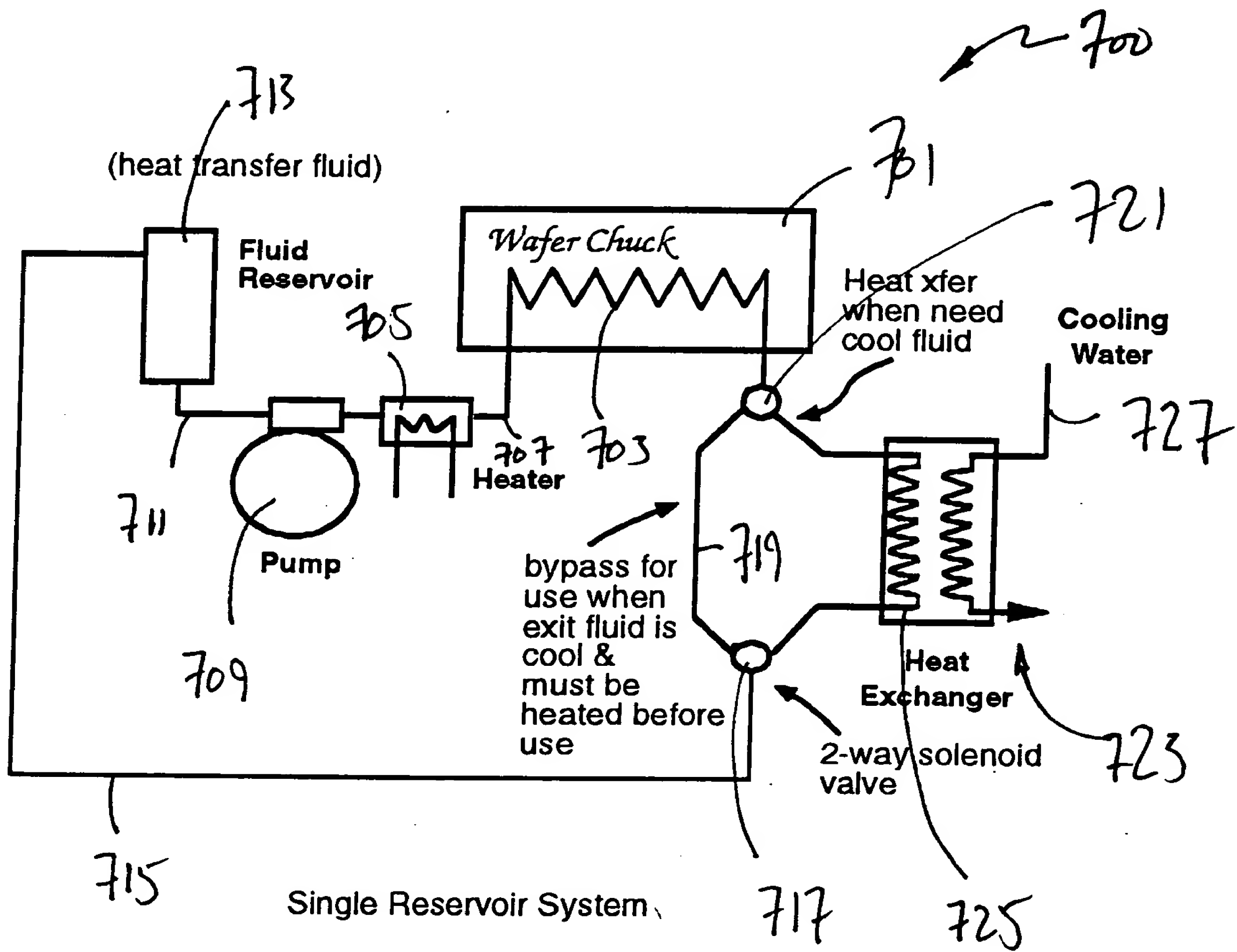


FIG. 7

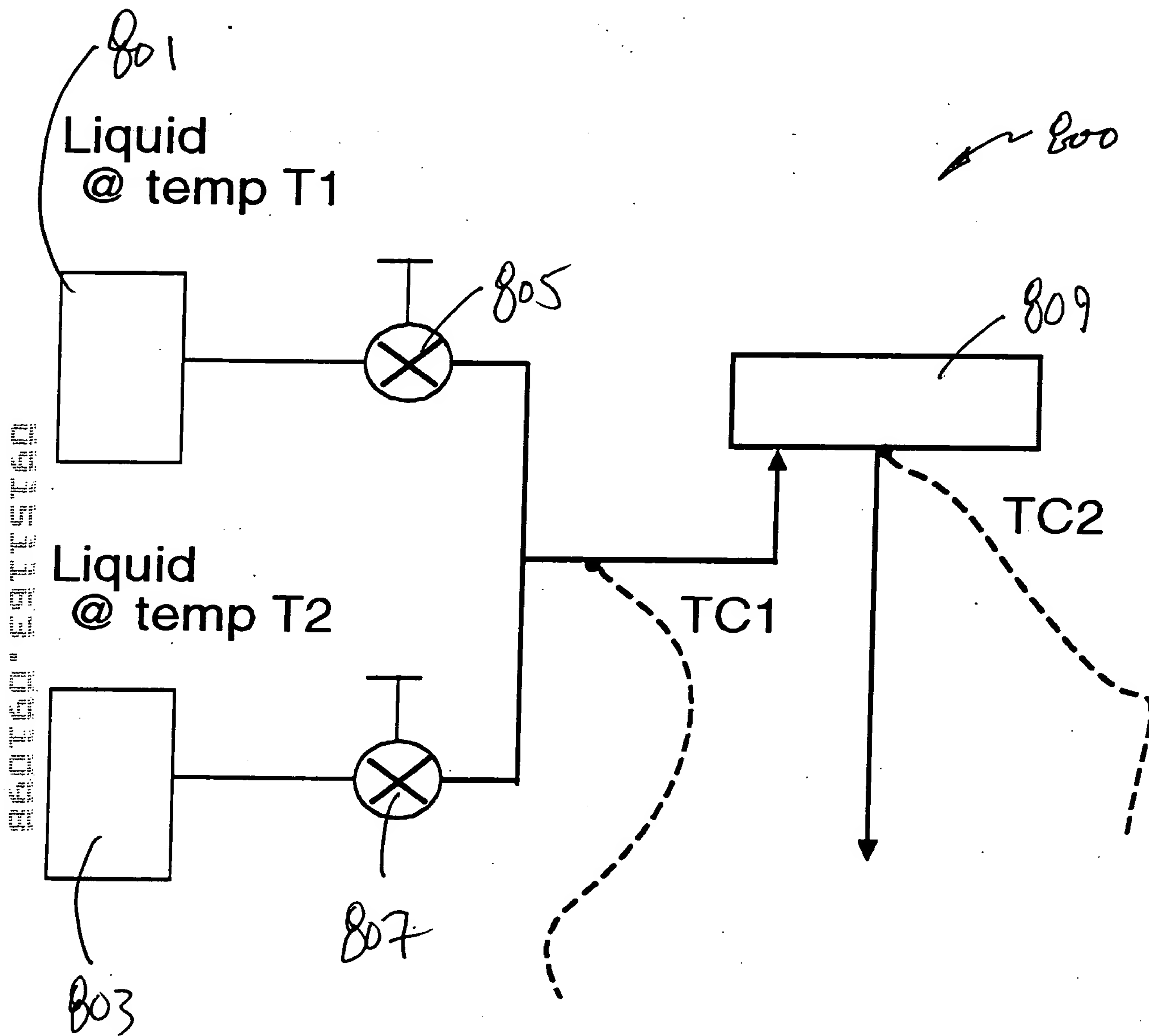


FIG. 8

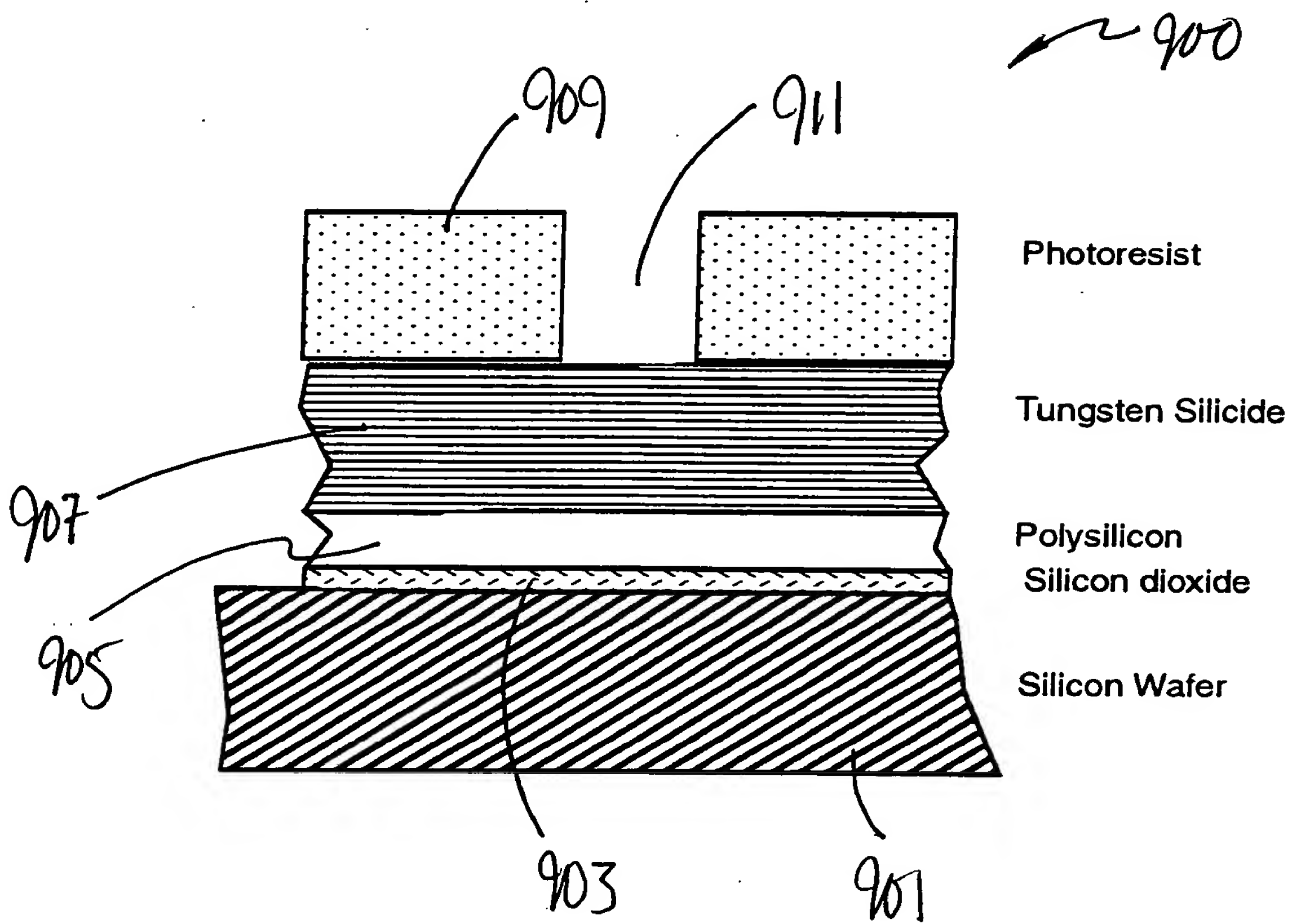
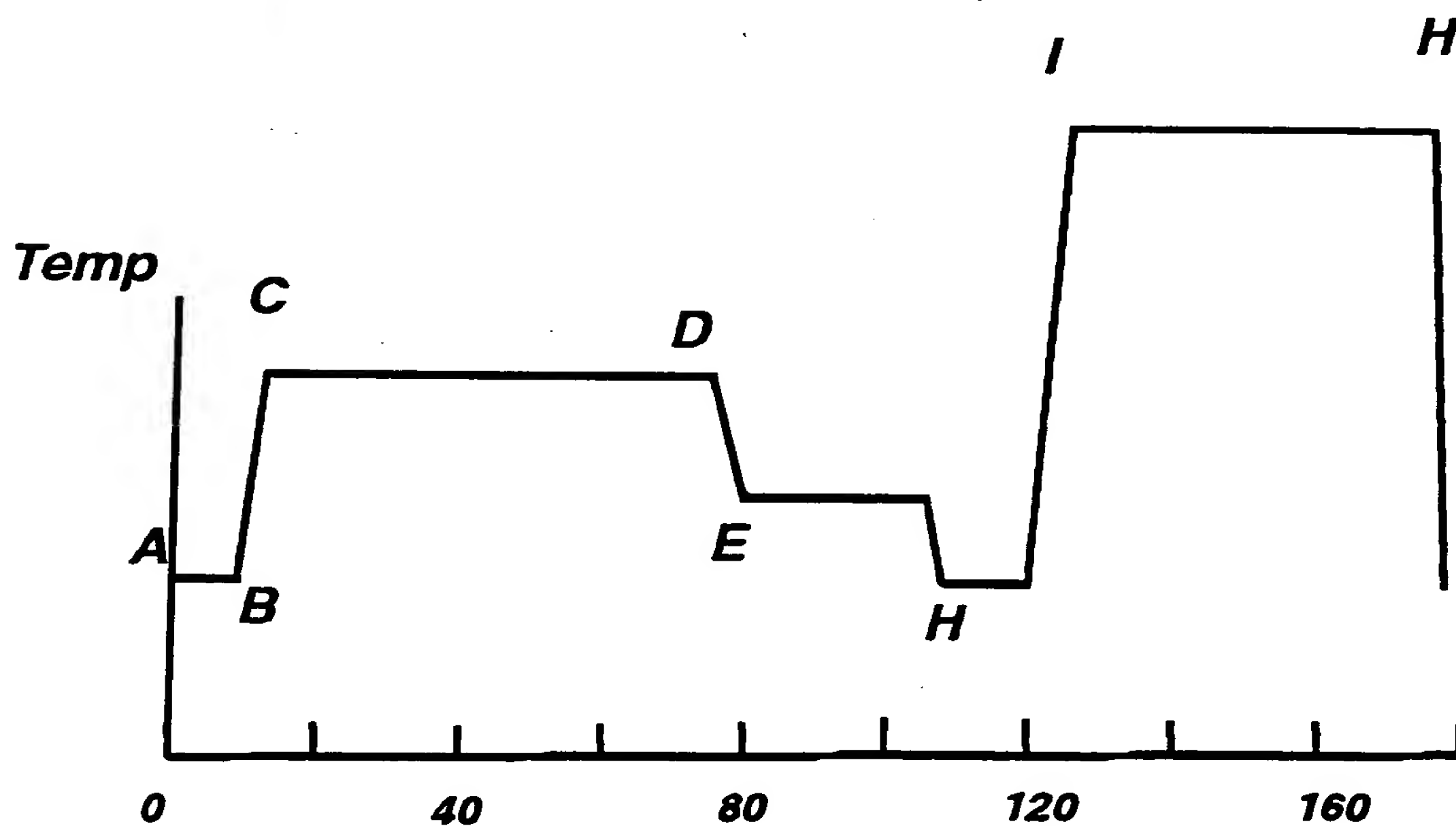
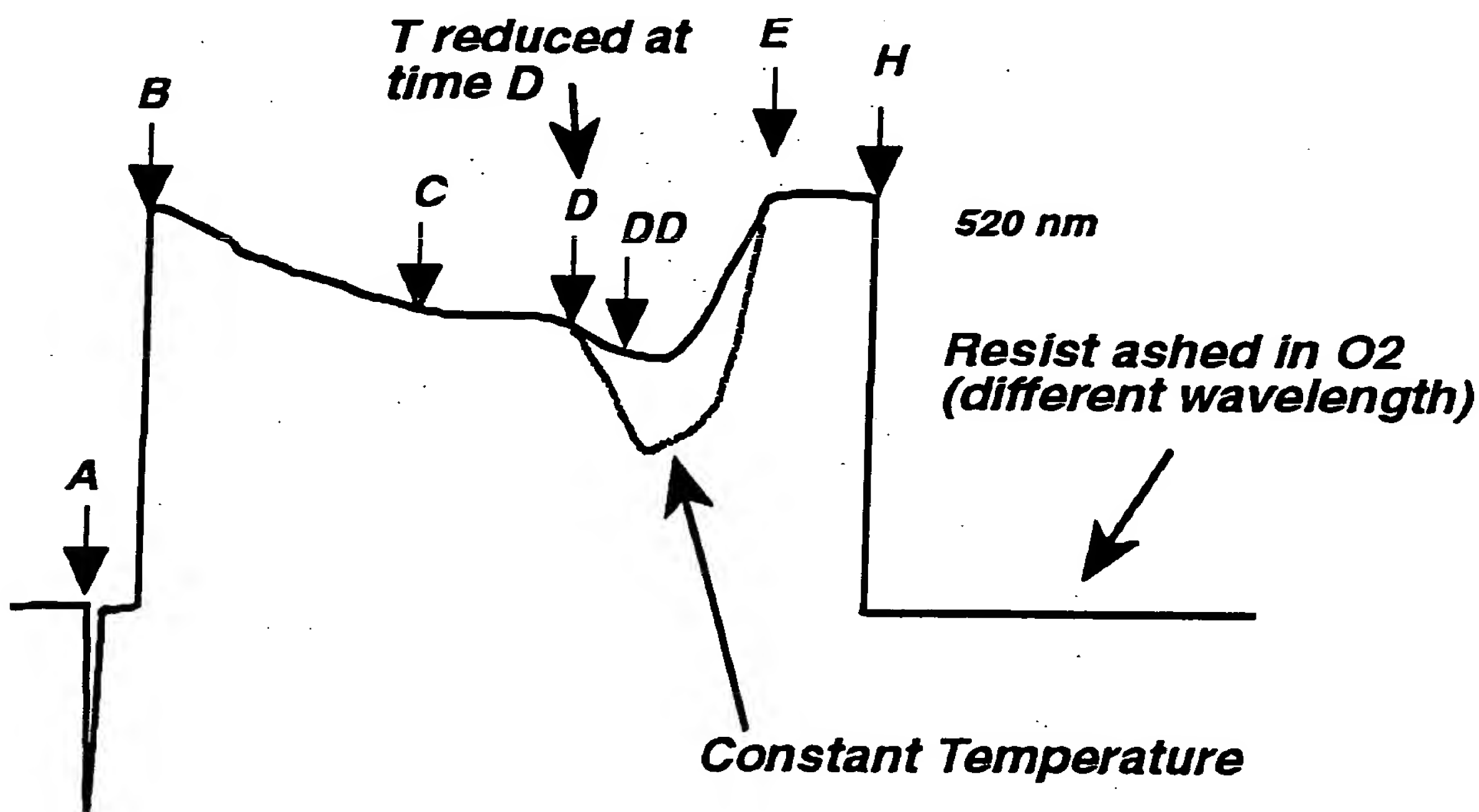


FIG. 9



- A.  $\text{SF}_6$  native oxide "breakthrough"
- B.  $\text{Cl}_2$  plasma is ignited
- C.  $\text{WSi}_x$  begins to clear (endpoint)
- D. Polysilicon is exposed
- E. Polysilicon cleared to oxide
- H. Plasma extinguished and  $\text{O}_2$  feed gas flow is started
- I.  $\text{O}_2$  plasma is started
- J  $\text{O}_2$  plasma is extinguished.

FIG. 10